PATENT COOPERATION TREATY

From the

	IN	TERNATIONAL	SEARCHING	AUTHORITY
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To: JANG, Seong Ku 17th Fl., KEC Building, 275-7 Yangjae-Dong, Seocho-Ku Seoul 137-130 Republic of Korea		PCT WRITTEN OPINION OF THE INTERNATIONAL SEARCHING AUTHORITY (PCT Rule 43bis.1)	
		Date of mailing (day/month/year) 2	29 DECEMBER 2004 (29.12.2004)
Applicant's or agent's file reference PIA40319M2N		FOR FURTHER A	CTION See paragraph 2 below
International application No. PCT/KR2004/000741	International filing date 31 MARCH 2004		Priority date(day/month/year)
International Patent Classification (IPC) of IPC7 H01L 21/306 Applicant M2N INC. et al	or both national classific	cation and IPC	/
Box No. IV Lack of unity of X Box No. V Reasoned stater citations and exp Box No. VI Certain docume Box No. VII Certain defects Box No. VIII Certain observa 2. FURTHER ACTION If a demand for international preliminary Examining A other than this one to be the IPEA and opinions of this International Searchin If this opinion is, as provided above, or	nion tent of opinion with regard for invention ment under Rule 43bis. It planations supporting substants cited is in the international appartions on the international ary examination is made Authority ("IPEA") exceed the chosen IPEA has not be a grant Authority will not be a considered to be a written appropriate, with amende	(a)(i) with regard to nove the statement olication all application will be concept that this does not application to considered.	ly where the applicant chooses an Authority Bureau under Rule 66.1 bis(b) that written the applicant is invited to submit to the tion of 3 months from the date of mailing
For further options, see Form PCT/IS/ 3. For further details, see notes to Form 1			

Name and mailing address of the ISA/KR



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International application No.

PCT/KR2004/000741

1. With regard to the language, this opinion has been established on the basis of the international application in the language in which it was filed, unless otherwise indicated under this item.
This opinion has been established on the basis of a translation from the original language into the following language, which is the language of a translation furnished for the purposes of international search (under Rules 12.3 and 23.1(b)).
2. With regard to any nucleotide and/or amino acid sequence disclosed in the international application and necessary to the claimed invention, this opinion has been established on the basis of:
a. type of material
a sequence listing
table(s) related to the sequence listing
b. format of material
in wirtten format
in computer readable form
c. time of filing/furnishing contained in the international application as filed. filed together with the international application in computer readable form. furnished subsequently to this Authority for the purposes of search.
3. In addition, in the case that more than one version or copy of a sequence listing and/or table relating thereto has been
filed or furnished, the required statements that the information in the subsequent or additioanl copies is identical to that in the application as filed or does not go beyond the application as filed, as appropriate, were furnished.
4. Additional comments:

WRITTEN OPINION OF THE INTERNATIONAL SEARCHING AUTHORITY

International application No.

PCT/KR2004/000741

Box No. V Reasoned statement under Rule 43bis.1(a)(i) with regard to novelty, inventive step or industrial applicability; citations and explanations supporting such statement

Novelty (N)	Claims 1-12	YES
	Claims NONE	NO NO
Inventive step (IS)	Claims NONE	YES
	Claims 1-12	NO
Industrial applicability (IA)	Claims 1-12	YES
	Claims NONE	NO

2. Citations and explanations:

1. Reference is made to the following documents:

D1: JP 08-313541(OLYMPUS OPTICAL CO LTD)

Claims 1 to 11 describe a method for fabricating a probe for a scanning probe microscope, comprising (a) forming a first mask to define a pattern for a tip and a second mask to define a pattern for a cantilever on an SOI wafer having a handle layer, an insulation layer and a device layer, (b) etching the device layer by using the first and second masks, (c) forming a sidewall passivation layer on the device layer, (d) etching the device layer by using the first mask to form the tip and (e) etching the handle layer by using a third mask to define a pattern for a mounting block. And claim 12 describe a probe for a scanning probe microscope using the method.

Document D1 discloses a method for manufacturing a cantilever for scanning probe microscope, comprising (a) preparing a bonded substrate(108) obtained by sticking a second substrate(106) to an oxide film formed on one surface of a first substrate(102), (b) shaping the substrate(106) in the shape of a lever section, (c) forming an oxide film(112) on the side end face of the lever section, (d) forming a probe section at part of the lever section after etching the substrate(106) to a prescribed thickness and (e) forming a supporting section in the substrate(102) after forming a oxide film on the surface of the substrate(106).

2. Novelty:

D1, which is considered to represent the most relevant state of the art, discloses a method for manufacturing a cantilever for scanning probe microscope from which the subject-matter of claim 1 differs in that the method includes a step of etching the device layer by using the first mask to form the tip. Thus, the subject-matter of claim 1 is novel under PCT Article 33(2). As a consequence, the subject-matter of the dependent claims 2-11 is novel. And the subject-matter of claim 12 is also novel.

3. Inventive step:

The subject-matter of claims 1-12, concerning a method for fabricating a probe for a scanning probe microscope and a probe for a scanning probe microscope, is not regarded as involving step, since said subject-matter is derivable from the D1.